

ABSTRACT

5 A substrate processing apparatus includes a reaction  
chamber for simultaneously processing a plurality of process  
substrates, a boat for loading the process substrates into  
the reaction chamber, and a stocker for storing a multiple  
number of dummy substrates, at least a portion of the dummy  
substrates being loaded into the reaction chamber together  
with the process substrates through the use of the boat. A  
10 substrate cleaning process is carried out by loading dummy  
substrates to be cleaned into the reaction chamber through  
the use of the boat and introducing a cleaning gas into the  
reaction chamber.

09911741.072501